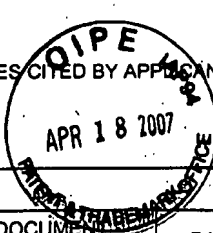
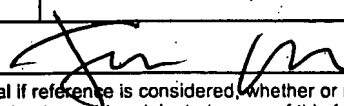


4/18/07

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 243028US0DIV		SERIAL NO. NEW APPLICATION	
LIST OF REFERENCES CITED BY APPLICANT <div style="text-align: center;"></div>				APPLICANT Toshimitsu TETSUI, et al.		10/667651	
				FILING DATE HEREWITH		GROUP 1742	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	5,226,985	07-13-93	Y-W. KIM et al.			
	AB	5,338,729	09-24-90	Y-W. KIM, et al.			
	AC	5,442,847	08-22-95	S.L. SEMIATIN, et al.			
	AD	5,846,351	12-08-98	N. MASAHASHI, et al.			
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO	64-042539	02-14-89	JAPAN			X
	AP	1-298127	12-01-89	JAPAN			X
	AQ	6-049565	02-22-94	JAPAN			X
	AR	6-041661	02-13-94	JAPAN			X
	AS	62-000215	01-06-87	JAPAN (no abstract available)			X
	AT	4-066830	03-03-92	JAPAN			X
	AU	4-124236	04-24-92	JAPAN			X
	AV	6-49024	02-22-94	JAPAN			X
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	D. ZHANG et al., Intermetallics, Vol. 7, No. 10, XP-004177382, pps. 1081-1087, "Characterization of Controlled Microstructures in A TiAl (Cr, Mo, Si, B) ALLOY," October 1999.					
	AX	"ASM Handbook: Vol. 3 Alloy Phase Diagrams," ASM International, 1992, p. 254.					
	AY						
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner 					Date Considered 7/5/07		
<small>*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

*The above crossed out references have been previously considered